

**COMPLEX ELECTRON MICROSCOPE**

Patent Number: JP2002343294  
Publication date: 2002-11-29  
Inventor(s): KONDO KOJIN  
Applicant(s): JEOL LTD  
Requested Patent: JP2002343294  
Application Number: JP20020063728 20020308  
Priority Number(s):  
IPC Classification: H01J37/28; H01J37/26  
EC Classification:  
Equivalents:

---

**Abstract**

---

**PROBLEM TO BE SOLVED:** To provide a complex electron capable of obtaining accurate correspondence between the SEM/STEM image and TEM image.

**SOLUTION:** This complex electron microscope, capable of observing the SEM/STEM image and the TEM image, is provided with a first storage means 44 for storing SEM/STEM image rotation angle, magnification of the TEM image and the current value supplied to an imaging lens, in order to make the TEM image correspond to the SEM/STEM image rotation angle; a second storage means 45 for storing the magnification of the TEM image and the rotation angle, in order to make the SEM/STEM image correspond to the TEM image rotation angle; a computer 40 for correcting the magnification and the rotation angle according to the display mode, based on the data stored in the first and the second storage means; and a display means 35 for displaying the image corrected by the computer 40.

---

Data supplied from the **esp@cenet** database - I2